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(54) SEMICONDUCTOR TEST SYSTEM

(57)Abstract:

PROBLEM TO BE SOLVED: To realize a semiconductor test system with high throughput, which is completely automated and free from an operator.

SOLUTION: The semiconductor test system is composed of a navigation system which makes up all conditions required for photographing/testing from design information, and a scanning electron microscope system which actually carries out photographing/testing, and then the all conditions required for photographing/testing are made up from the design information such as CAD data or the like, and the actual test is carried out in those conditions. The variation of shape is compensated using information of the edge in every direction and a smoothing method in the case a matching process between design data and a SEM image is carried out. Furthermore, the SEM image corresponding to a detected position is registered again as a template, and the matching process is carried out.

